



Form 1449 (Modified)

**Information Disclosure
Statement By Applicant**

(Use Several Sheets if Necessary)

Atty Docket No.
LAM1P128D1

Applicant:
Hemker et al.

Filing Date
July 11, 2003

Application No.:
10/618,289

Group
1765

U.S. Patent Documents

Examiner Initial	No.	Patent No.	Date	Patentee	Class	Sub- class	Filing Date
MAA	A1	4,948,458	08/14/90	Ogle			08/14/89
	A2	4,990,229	02/05/91	Campbell et al.			06/13/89
	A3	5,091,049	02/25/92	Campbell et al.			06/29/90
	A4	5,122,251	06/16/92	Campbell et al.			02/04/91
	A5	5,421,891	06/06/95	Campbell et al.			10/19/92
	A6	5,429,070	07/04/95	Campbell et al.			11/20/92
	A7	5,587,038	12/24/96	Cecchi et al.			06/16/94
	A9	5,810,932	09/22/98	Ueda et al.			08/05/96
	A10*	5,021,114	06/04/91	Saito et al.			07/19/88
	A11*	5,032,205	07/16/91	Hershkowitz et al.			05/05/89
	A12*	5,226,967	07/13/93	Chen et al.			05/14/92
	A13*	5,401,350	03/28/95	Patrick et al.			03/08/93
	A14*	5,540,800	07/30/96	Qian			06/23/94
	A15*	5,587,205	12/24/96	Saito et al.			12/23/93
	A16*	5,669,975	09/23/97	Ashtiani			03/27/96
	A17*	5,811,022	09/22/98	Savas et al.			11/15/94
	A18*	6,030,486	02/29/00	Loewenhardt et al.			12/16/96
	A19*	6,096,160	08/01/00	Kadomura			04/16/97
Examiner	Matthew Anderson			Date Considered 7/24/2005			

Examiner: Initial citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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Foreign Patent or Published Foreign Patent Application

Examiner Initial	No.	Document No.	Publication Date	Country or Patent Office	Class	Sub- class	Translation	
							Yes	No
MAA	B1	EP 0838843 A2	04/29/98	EPO				
MAA	B2	EP 0821397 A2	01/28/98	EPO				
MAA	B3	WO 99/50866	10/07/99	PCT				
MAA	B4*	05267237	10/15/93	EP				
MAA	B5*	09139380	05/27/96	EP				
MAA	B6*	2231197	11/07/90	GB				
MAA	B7*	4-329875	11/08/92	JP.				

Other Documents

Examiner Initial	No.	Author, Title, Date, Place (e.g. Journal) of Publication
MAA	C1	Japanese Application No. 04094953, filed March 1992, entitled "PLASMA DAMAGE REDUCTION AND PLASMA PROCESSOR, by Minegishi Kazushige, Patent Abstracts of Japan, Vol. 18, No. 33.
MAA	C2	Japanese Application No. 08255259, filed August 1996, entitled "PLASMA DAMAGE REDUCTION AND PLASMA PROCESSOR, by Minegishi Kazushige, Patent Abstracts of Japan, Vol. 18, No. 33.
MAA	C3*	Office Action dated March 28, 2001 for U.S. Application No. 09/439,661, entitled "PLASMA PROCESSING SYSTEMS," filed on November 15, 1999, now U.S. Patent No. 6,341,574 B1.
MAA	C4*	Office Action dated June 27, 2001 for U.S. Application No. 09/439,661, entitled "PLASMA PROCESSING SYSTEMS," filed on November 15, 1999, now U.S. Patent No. 6,341,574 B1.
Examiner	<i>Matthew Anderson</i> Date Considered <i>7/24/2005</i>	

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